

**Notice of References Cited**

Application/Control No.

10/019,666

Applicant(s)/Patent Under  
Reexamination  
KIM ET AL.

Examiner

David M Brunsman

Art Unit

1755

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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,767,030	06-1998	Kim et al.	501/136
	B	US-5,916,030	06-1999	Warner, Gregory K.	472/65
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	CAPLUS 2003:354765, Kim et al, "Structure and microwave dielectric properties...", 2003
	V	CAPLUS 1999:593074, Kim et al, "Microwave dielectric ceramics..." 1999
	W	CAPLUS 1999:818005, Kim et al. "Low-temperature sintering and..." 1999
	X	CAPLUS 2000:41577, Kim et al., "Low-fired (Zn,Mg)TiO3 microwave dielectrics" 2000

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

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	U	CAPLUS 2000:896800, Purvanova et al, "Preparation and some properties of..." 1999
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